

# EUROPEAN PATENT OFFICE

## Patent Abstracts of Japan

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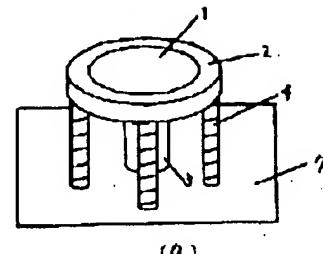
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APPLICANT : SEIKO EPSON CORP;

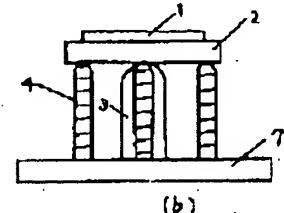
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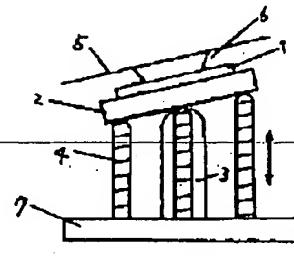
TITLE : WAFER PROBER



(a)



(b)



(c)

ABSTRACT : PURPOSE: To realize a probing operation where a stage is not required to be adjusted so as to enhance a probe card in mounting accuracy by a method wherein a mechanism which adjusts the stage in horizontal angle is mounted on the stage.

CONSTITUTION: Three or more arms 4 which move up or down by a cylinder or a motor or the like are fixed to a stage 2 at a regular interval. If a probe card 5 is not horizontal, the arms 4 are made to move up or down, whereby the stage 2 can be freely controlled in angle of inclination so as to be parallel with the probe card 5. At this point, the center of the stage 2 is kept constant in position. By this setup, a probing operation can be executed without taking the mounting accuracy of a probe card into consideration.

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